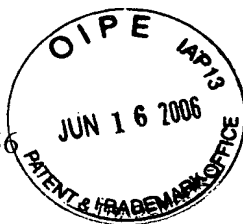


Attorney Docket: 081468-0307456
Client Reference: P-1794.000-US



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
BANINE ET AL.

Confirmation Number: 2894

Application No.: 10/747,613

Group Art Unit: 2851

Filed: December 30, 2003

Examiner: Della J. Rutledge

Title: LITHOGRAPHIC APPARATUS AND RADIATION SOURCE COMPRISING A
DEBRIS-MITIGATION SYSTEM AND METHOD FOR MITIGATING DEBRIS PARTICLES
IN A LITHOGRAPHIC APPARATUS

RESPONSE TO OFFICE ACTION

United States Patent and Trademark Office
Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

In response to the Office Action dated February 24, 2006, a response to which being due on June 24, 2006 with a one-month extension of time being filed herewith, please take the following remarks into consideration:

06/19/2006 SZEWDIE1 00000158 033975 10747613
01 FC:1251 120.00 DA